

A2 --Description of the Related Art--

Page 5, before line 7, please insert:

--SUMMARY OF THE INVENTION--

A3

Page 8, before line 4, please insert:

--BRIEF DESCRIPTION OF THE FIGURES OF THE DRAWINGS--

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Page 8, before line 25, please insert:

--DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENTS--

A5

IN THE CLAIMS:

Please replace Claims 4, 6 and 8-13 as follows:

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A6
4. (Amended) Control method according to Claim 1, characterized in that the ellipsometric measurement is one with phase modulation.

6. (Amended) Control method according to Claim 1, characterized in that the ellipsometric measurement is carried out using the method called "rotating polarizer" method.

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Cont'd.
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8. (Amended) Control method according to Claim 1, characterized in that the ellipsometric measurement is a multiwavelength measurement.

9. (Amended) Control method according to Claim 1, characterized in that the reference values form a theoretically determined path.

10. (Amended) Control method according to Claim 1, characterized in that the reference values form an experimentally determined path.

11. (Amended) Control method according to Claim 1, characterized in that the reference values are discrete points corresponding to the instants of fabrication of the thin layers with respect to the time t_0 .

12. (Amended) Control method according to Claim 1, characterized in that the path traveled is adjusted by a polynomial of order between 1 and 5.

13. (Amended) Control method according to Claim 1, characterized in that the reference values are determined by measurement, using the succession of the following steps:

- measurement of a known layer on a simple substrate;
- measurement of the same known layer on an industrial substrate;
- measurement of the thin-film structure to be controlled.

Please add the following new Claims 14-33:

32 added.
--14. (New) Control method according to Claim 2, characterized in that the ellipsometric measurement is one with phase modulation.

15. (New) Control method according to Claim 3, characterized in that the ellipsometric measurement is one with phase modulation.

16. (New) Control method according to Claim 14, characterized in that the measured variables are, respectively:

$$I_s = (\sin 2\Psi \sin \Delta) \text{ and}$$

$$I_c = (\sin 2\Psi \cos \Delta) \text{ or } I_c = \cos 2\Psi.$$

17. (New) Control method according to Claim 14, characterized in that the measured variables are, respectively:

$$I_s = (\sin 2\Psi \sin \Delta) \text{ and}$$

$$I_c = (\sin 2\Psi \cos \Delta) \text{ or } I_c = \cos 2\Psi.$$

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18. (New) Control method according to Claim 2, characterized in that the ellipsometric measurement is carried out using the method called "rotating polarizer" method.

19. (New) Control method according to Claim 3, characterized in that the ellipsometric measurement is carried out using the method called "rotating polarizer" method.

20. (New) Control method according to Claim 18, characterized in tht the measured variables are $\tan \Psi$ and $\cos \Delta$.

21. (New) Control method according to Claim 19, characterized in tht the measured variables are $\tan \Psi$ and $\cos \Delta$.

22. (New) Control method according to Claim 2, characterized in that the ellipsometric measurement is a multiwavelength measurement.

23. (New) Control method according to Claim 3, characterized in that the ellipsometric measurement is a multiwavelength measurement.

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24. (New) Control method according to Claim 2, characterized in that the reference values form a theoretically determined path.

25. (New) Control method according to Claim 3, characterized in that the reference values form a theoretically determined path.

26. (New) Control method according to Claim 2, characterized in that the reference values form an experimentally determined path.

27. (New) Control method according to Claim 3, characterized in that the reference values form an experimentally determined path.

28. (New) Control method according to Claim 2, characterized in that the reference values are discrete points corresponding to the instants of fabrication of the thin layers with respect to the time t_0 .

29. (New) Control method according to Claim 3, characterized in that the reference values are discrete points corresponding to the instants of fabrication of the thin layers with respect to the time t_0 .

30. (New) Control method according to Claim 2, characterized in that the path traveled is adjusted by a polynomial of order between 1 and 5.

31. (New) Control method according to Claim 3, characterized in that the path traveled is adjusted by a polynomial of order between 1 and 5.

32. (New) Control method according to Claim 2, characterized in that the reference values are determined by measurement, using the succession of the following steps:

- measurement of a known layer on a simple substrate;
- measurement of the same known layer on an industrial substrate;
- measurement of the thin-film structure to be controlled.

33. (New) Control method according to Claim 3, characterized in that the reference values are determined by measurement, using the succession of the following steps:

- measurement of a known layer on a simple substrate;
- measurement of the same known layer on an industrial substrate;
- measurement of the thin-film structure to be controlled.--